

ASML PAS5500/80B "AS IS" Serial nr 6176 Vintage 1993

Information contained in this presentation is confidential

The PAS 5500/80, 0.48NA i-line stepper is designed for mass production at 0.5 µm and achieves extremely high throughput the manufacturing of multiple generations of half-micron design rules by optimizing both depth of focus and resolution for critical process layers.

- Manufacturer: ASML, the Netherlands
- Model: PAS 5500/80, i-line stepper
- Vintage: 1993
- Reduction ratio: 1:5
- Wafer size 4-8 inch (currently at 6 inch)
- Field size: 21 mm x 21 mm
- Design resolution: 0.50 um

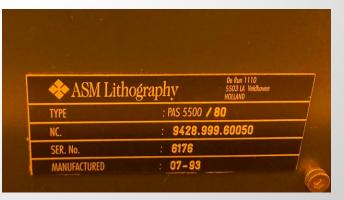




#### OPTIONS

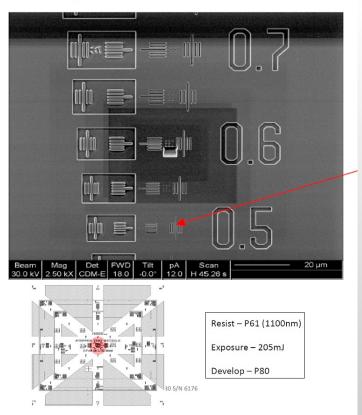
# SECS SINGLE\_RETICLE\_SMIF PEP\_1\_PRODUCTIVITY\_UPGRADE MARK\_SENSOR BATCH\_STREAMING







#### Reticle Layout data and measurement Points

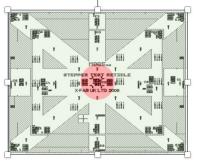




#### 0.5 Measurement Feature Data

Mean	Range	Sigma		
0.503um	0.021um	0.0063um		

E5		E3		E1
0.502		0.5		0.489
	D4	D3	D2	
	0.496	0.502	0.506	
C5	C4	C3	C2	C1
0.49	0.497	0.5	0.508	0.498
	B4	B3	B2	
	0.51	0.495	0.502	
A5		A3		A1
0.501		@512		0.504



PAS5500/80 S/N 6176

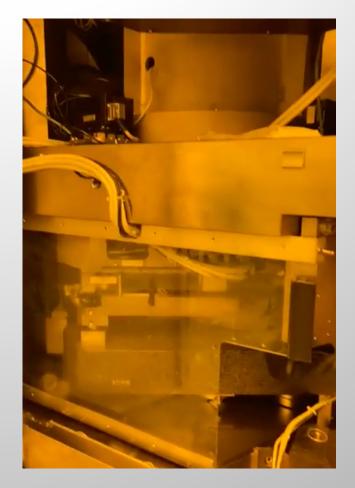




Operator:EQP	Machin	e:6176	Re	lease	:8.8.6	Date:10/05	/2022	Time:16:03
Stray Light Meas	uremen	t						
Comment	: Un	iformit	y str	ay li	ght measur	rement		
Image Field Size X		21.0	у:	21	.0			
Steps X		11	у:	11				
Apply REMA Windo	w : Ye	s						
Load Reticle	: N							
Stray Light Meas Maximum Stray Stray Light Va Log Files	Light	Number	[%] :	1	.81	723, LI/LIU	JM/waf.	4724

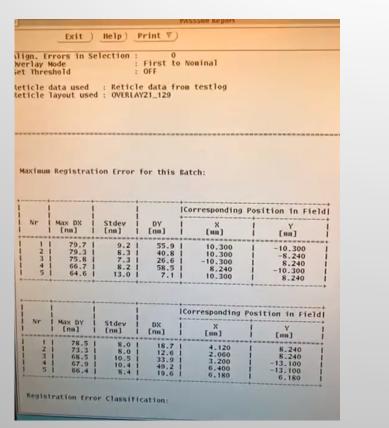
Uniformity Measurement
Comment :
Image Field Size [mm] x : 21.0 y : 21.0 Diameter : 29.7
Steps x : 11 y: 11
Measurement Type : Sample Mode
Lamp Power [W] : 1000.0
Samples per Position : 50
Apply REMA Window : Yes
Load Reticle : N
Uniformity Measurement Result
Uniformity [%] : 1.30 Logfile : LI/LIUM/waf.4765 Number of valid measurements : 121
Tilt X [%/field] : 0.77 Y [%/field] : 1.15
Overall Average of Ratio : 1.01 Standard Deviation : 0.01 Intensities Spot Sensor [mW/cm2] : 327.77 Standard Deviation : 1.78 Intensities Energy Sensor [mW/cm2] : 324.83 Standard Deviation : 0.20
Lamp Time Lit [hour] : 221:24
Estimated Uniformity from measured data [%] If corrected for actual tilts : 1.04 If corrected with gradient filter : 1.12 If corrected for tilts and with gradientfilter : 0.60
Symmetric Uniformity Value [%] : -0.74

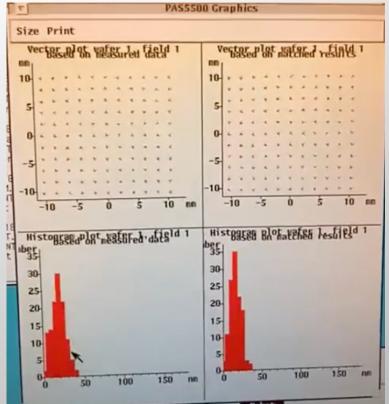






#### **Overlay First to Nominal & machine to machine**







- Prior to de-install
  - Full inspection including performance checks while system still in manufacturing
  - Production wafers cycled prior to de-install, including reticle exchanges.
- De-install
  - Original ASML locking material used
  - Packed according to ASML conditions
- Transport
  - Shock recorders were installed and packing was done according to ASML transport condition
- Storage
  - Storage at warehouse in Singapore, according to ASML storage conditions
  - Lens under continuos lens purge

## **Solutions on Silicon BV**

#### Your service partner for LAM Research Equipment

#### • Equipment Support

PM, CM, Trouble shooting, Upgrading, Training and Onsite Service Contracts

#### Process Support

Process design, Improvement, Fab-to-Fab Transfer and Integration

#### Refurbishment

From custom to complete refurbishment

#### Relocation

Auditing, Fingerprinting, Decommissioning, Installation, Acceptance

#### • Materials Supplier of first class second source materials

• Contact

Ronald Melief ron.melief@nextlevel4u.nl



